

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S1	8	"6195201".uref.	US-PGPUB; USPAT; DERWENT	OR	ON	2005/03/31 10:38
S2	1705271	(lithograph\$4 or ((mask or reticle) or (wafer or substrate)))	US-PGPUB; USPAT; DERWENT	OR	ON	2005/03/31 10:40
S3	7339	(reconfigur\$5 or adjustable or program\$5) near4 mirror	US-PGPUB; USPAT; DERWENT	OR	ON	2005/06/13 13:52
S4	1983	S2 and S3	US-PGPUB; USPAT; DERWENT	OR	ON	2005/03/31 10:42
S5	18	S4 and faceted near3 mirror	US-PGPUB; USPAT; DERWENT	OR	ON	2005/03/31 10:42
S6	3	(reconfigur\$5 or adjustable or program\$5) near4 mirror same first near2 (exposure or pattern\$3) same second near3 (exposure or pattern\$3)	US-PGPUB; USPAT; DERWENT	OR	ON	2005/03/31 10:51
S7	1	electronic\$4 near4 mirror same first near2 (exposure or pattern\$3) same second near3 (exposure or pattern\$3)	US-PGPUB; USPAT; DERWENT	OR	ON	2005/03/31 11:14
S8	64	(reconfigur\$5 or adjust\$4 or program\$5 or electronic\$4) near5 (mirror or reflect\$3) same first near2 (exposure or pattern\$3) same second near3 (exposure or pattern\$3)	US-PGPUB; USPAT; DERWENT	OR	ON	2005/03/31 10:52
S9	1	"5359441".PN.	USPAT; USOCR	OR	ON	2005/03/31 10:58
S10	1	"5486485".PN.	USPAT; USOCR	OR	ON	2005/03/31 10:59
S11	1	"6023309".PN.	USPAT; USOCR	OR	ON	2005/03/31 10:59
S12	1	"6061110".PN.	USPAT; USOCR	OR	ON	2005/03/31 10:59
S13	1	"6285488".PN.	USPAT; USOCR	OR	ON	2005/03/31 10:59
S14	1	"6509955".PN.	USPAT; USOCR	OR	ON	2005/03/31 11:01
S15	1	"6624880".PN.	USPAT; USOCR	OR	ON	2005/03/31 11:01
S16	1	"6642984".PN.	USPAT; USOCR	OR	ON	2005/03/31 11:03

S17	82	(micromirror or slm or spacial adj light adj modulator) same first near2 (exposure or pattern\$3) same second near3 (exposure or pattern\$3)	US-PGPUB; USPAT; DERWENT	OR	ON	2005/03/31 11:15
S18	78	S2 and S17	US-PGPUB; USPAT; DERWENT	OR	ON	2005/03/31 11:15
S19	17126	(slm or spacial adj light adj modulat\$3 or micro adj mirror or micromirror or dmd or deformable adj mirror adj device)	US-PGPUB; USPAT; DERWENT	OR	ON	2005/04/08 09:39
S20	162	S19 and 355/53,67-71.ccls.	US-PGPUB; USPAT; DERWENT	OR	ON	2005/04/08 09:28
S21	149	S20 and (lithograph\$2 or photolithograph\$3 or microlithograph\$3 or (reticle or mask) or (wafer or substrate))	US-PGPUB; USPAT; DERWENT	OR	ON	2005/04/08 09:29
S22	2057	(plural\$3 or multiple or two or second) near2 (slm or spacial adj light adj modulat\$3 or micro adj mirror or micromirror or dmd or deformable adj mirror adj device)	US-PGPUB; USPAT; DERWENT	OR	ON	2005/04/08 09:40
S23	61	S21 and S22	US-PGPUB; USPAT; DERWENT	OR	ON	2005/04/08 09:40
S24	2	"6195201".pn.	US-PGPUB; USPAT; DERWENT	OR	ON	2005/05/13 10:59
S25	9	(polygon or steering) near2 mirror near2 ((dmd or digital adj mirror adj device) or slm or spacial adj light adj modulat\$3)	US-PGPUB; USPAT; DERWENT	OR	ON	2005/05/20 09:20
S26	0	(polygon or steering) near2 mirror near2 ((dmd or digital adj mirror adj device) or slm or spacial adj light adj modulat\$3)	EPO; JPO; DERWENT	OR	ON	2005/05/20 09:20
S27	0	(polygon or steering) near2 mirror near2 (programmable or digital) near2 mirror adj (array or device)	EPO; JPO; DERWENT	OR	ON	2005/05/20 09:24
S28	0	(polygon or steering) near2 mirror near2 (programmable or digital) near2 mirror adj (array or device)	US-PGPUB; USPAT; DERWENT	OR	ON	2005/05/20 09:24
S29	0	(polygon or steering) near2 mirror near4 (programmable or digital) near2 mirror adj (array or device)	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	ON	2005/05/20 09:24

S30	105	"5212582".uref.	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	ON	2005/05/20 09:25
S31	26	S30 and (dmd or slm or spacial adj light adj modulat\$3 or (digital or programmable) adj mirror or steering near2 mirror)	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	ON	2005/05/20 10:27
S32	4	("5691541" or "6379867").pn.	US-PGPUB; USPAT; DERWENT	OR	ON	2005/05/31 10:56
S33	4	("5512759" or "5677939" or "539346" or "5631721" or "5361292").pn.	USPAT	OR	ON	2005/06/13 13:42
S34	146	(reconfigur\$5 or modifiable or program\$5) near4 condenser	US-PGPUB; USPAT; DERWENT	OR	ON	2005/06/13 14:01
S35	1743145	(lithograph\$4 or ((mask or reticle) or (wafer or substrate)))	US-PGPUB; USPAT; DERWENT	OR	ON	2005/06/13 14:03
S36	18	S34 and S35	US-PGPUB; USPAT; DERWENT	OR	ON	2005/06/13 13:54
S37	27	(reconfigur\$5 or modifiable or program\$5) near4 condenser	EPO; JPO; DERWENT	OR	ON	2005/06/13 14:03
S38	70	(reconfigur\$5 or modifiable or program\$5) near4 condens\$3	EPO; JPO; DERWENT	OR	ON	2005/06/13 14:03
S39	1523689	(lithograph\$4 photolithograph\$3 or microlithograph\$3 or ((mask or reticle) or (wafer or substrate)))	EPO; JPO; DERWENT	OR	ON	2005/06/13 14:04
S40	1	S38 and S39	EPO; JPO; DERWENT	OR	ON	2005/06/13 14:06
S41	22	condens\$3 near2 (dmd or slm or mems or spatial adj light adj modulat\$3 or digital near2 mirror or mirror adj array)	EPO; JPO; DERWENT	OR	ON	2005/06/13 14:20
S42	93	condens\$3 near2 (dmd or slm or mems or spatial adj light adj modulat\$3 or digital near2 mirror or mirror adj array)	US-PGPUB; USPAT; DERWENT	OR	ON	2005/06/13 14:20